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Formation of Self-Focused Ion Beam

The formation of self-focused ion beam with a small diameter is proposed. The device for the formation of self-focused ion beam consists of a hollow anode and enveloped anode, separated from the anode by an insulator, gas delivery system. A discharge is supported by the voltage applied between the cathode and anode. The ion beam is self-focused by the spherical emission surface of emitting plasma.

The result of computer simulation of self-focused ion beam production is presented. The device for self-focused ion beam production is described.

Funding Agency

doe

Email Address

dvg43@yahoo.com

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Yes

Presenter if not the submitter of this abstract

Vadim Dudnikov

Primary author: DUDNIKOV, Vadim (retired)

Presenter: KALVAS, Taneli (University of Jyväskylä, Department of Physics)

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